

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re	Application of)	
Hiroki et al.		I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on (Date of Deposit)
Serial No.: 09/776,472		
Filed: February 2, 2001		
For:	Thin Film Formation Apparatus And) Method Of Manufacturing Self-Light-) Emitting Device Using Thin Film) Formation Apparatus)	Shannon Wallace Name of applicant assignee, or Registered Rep. Signature Shannon Wallace 7/6/06 Signature Date
Art Unit: 1762		
Exam	iner: Michael B. Cleveland)	
Comr	nissioner for Patents	
P.O. I	Box 1450	
Alexa	ndria, VA 22313-1450	

RESPONSE (I) AFTER FINAL

Sir:

Applicants have the following response to the Final Rejection of April 6, 2006. Applicants are filing a RCE herewith in order to have this response and the enclosed IDS entered and considered at this time.

Applicants will address each of the Examiner's rejections in the order in which they appear in the Final Rejection.